

# **INFORMATION DISCLOSURE STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet

1

of

2

Application Number

10/539,820

Filing Date

June 20, 2005

First Named Inventor

Jacob THAYSEN

Art Unit

Examiner Name

Attorney Docket Number

08845.0015

## **U.S. PATENTS AND PUBLISHED U.S. PATENT APPLICATIONS**

Examiner Initials	Cite No. <sup>1</sup>	Document Number Number-Kind Code <sup>2</sup> (if known)	Issue or Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
MN		US-4,311,980	January 19, 1982	Prudenziati	
MN		US-5,275,055	January 4, 1994	Zook et al.	

**Note: Submission of copies of U.S. Patents and published U.S. Patent Applications is not required.**

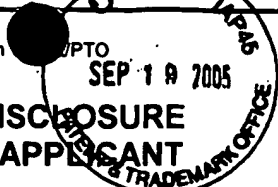
## **FOREIGN PATENT DOCUMENTS**

Examiner Initials	Cite No. <sup>1</sup>	Foreign Patent Document Country Code <sup>3</sup> Number <sup>4</sup> Kind Code <sup>5</sup> (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Translation <sup>6</sup>
MN		WO03/067248 A1	August 14, 2003	CANTION A/S Scion. Dtu		
MN		WO03/062135 A1	July 31, 2003	CANTION A/S		
MN		WO03/104794 A1	December 18, 2003	CANTION A/S		
MN		WO03/071258 A1	August 28, 2003	CANTION A/S		
MN		WO00/14539	March 16, 2000	AEA TECHNOLOGY PLC		
MN		WO00/66266	November 9, 2000	GREY ET AL		
MN		WO03/044530 A1	May 30, 2003	CANTION A/S		
MN		WO99/38007	July 29, 1999	CAMBRIDGE UNIVERSITY TECHNICAL SERVICES LTD.		

## **NON PATENT LITERATURE DOCUMENTS**

Examiner Initials	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation <sup>6</sup>
MN		H. Chen et al., "A Piezoresistive Accelerometer with a Novel Vertical Beam Structure", Sensors and Actuators, Vol. 63, pp. 19-25, 1997	
MN		Marc Madou: "Fundamentals of microfabrication" 1997, ISBN: 0-8493-9451-1, pp. 160-163.	
MN		Toriyama T et al: "Single crystal silicon nano-wire piezoresistors for mechanical sensors"; Journal of Microelectromechanical Systems, IEEE, Vol. 11, No. 5, pp. 605-611, October 2002.	
MN		Harley J. A et al.: "1/f noise considerations for the design and process optimization of piezoresistive cantilevers"; Journal of Microelectromechanical Systems IEEE, Vol. 9, No. 2, pp. 226-235, June 2000.	
MN		Jaeger R C et al.: "Off-axis sensor rosettes for measurement of the piezoresistive coefficients of silicon"; IEEE Transactions on Components, Hybrids, and manufacturing Technology, Vol. 16, No. 8, pp. 925-931, Dec. 1993.	
MN		Jacob Thaysen "Cantilever for Bio-Chemical Sensing Integrated in a Microliquid Handling System". Ph.D Thesis, Mikroelektronik Centret, September 2001.	
MN		Stanley W. Polchlopek et al, "Properties of Nitrogen-Implanted SOI Substrates", IEEE Transaction on electron devices. Vol. 40.No. 2, February 1993.	
MN		Thaysen J. et al., "Atomic Force Microscopy probe with piezoresistive read-out and high symmetrical Wheatstone bridge arrangement" Proceedings of Transducers '99, 1252-1855, pp. 47-53, (1999).	
MN		Thaysen et al. "Cantilever-based bio-chemical sensor integrated in a microliquid handling system".	

03/08/2007

IDS Form PTO/SB/08: Substitute for form PTO				<b>Complete if Known</b>	
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		Art Unit			
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Sheet	2	of	2	Attorney Docket Number	08845.0015

NON PATENT LITERATURE DOCUMENTS			
MN		Technical Digest, 14 <sup>th</sup> IEEE. International conference on micro electro mechanical systems. ISBN: 0-7803-5998-4, . 2001.	
MN		Samuel Kassegne et al: "Design Issues in SOI-Based High-Sensitivity Piezoresistive Cantilever Devices" ; Nanogen Inc.	
MN		S. M. SZE, "Classification and terminology of sensors", Semiconductor Sensors, ISBN 0-471-54609-7, John Wiley & Sons Inc., pp. 160-169, 1994.	
MN		Y Kanda, "A graphical representation of the piezoresistance coefficients in silicon" IEEE Trans. Electron Devices, Vol. ED-29, pp. 64-70, Jan. 1982.	

Examiner Signature	/Max Noori/	Date Considered	03/08/2007
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.